

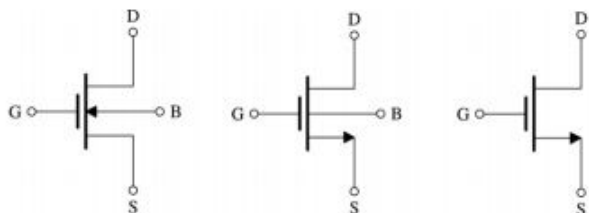
Unit 1

Current-Voltage Characteristics

Current-Voltage Characteristics

Circuit symbol

□ *n*-channel enhancement-mode MOSFET



The current-voltage characteristics

□ Cut-off region: ($v_{GS} \leq V_t$)

$$\rightarrow i_D = 0$$

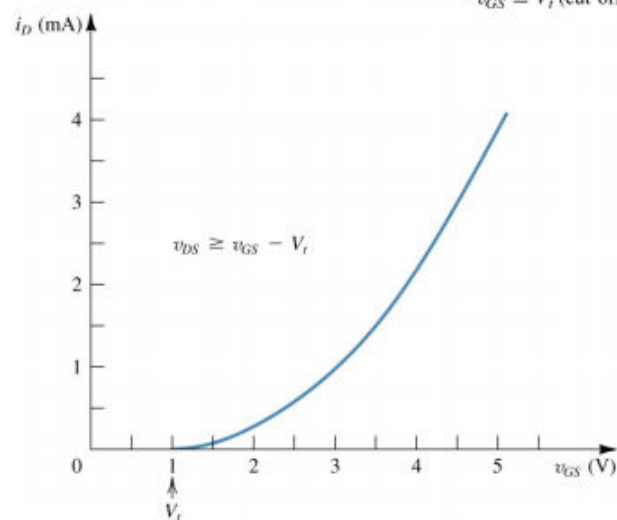
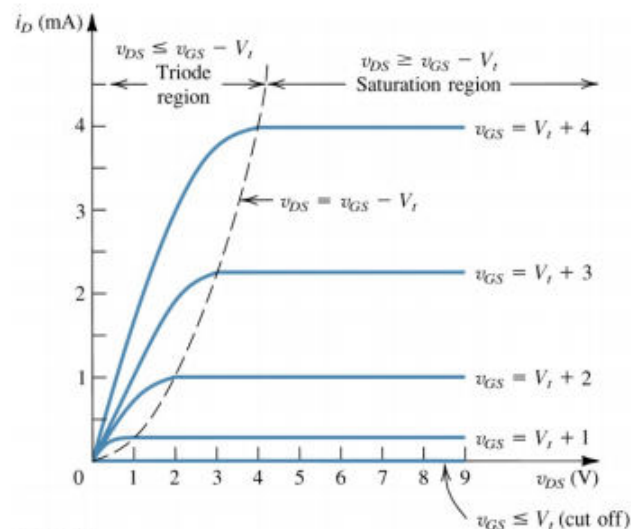
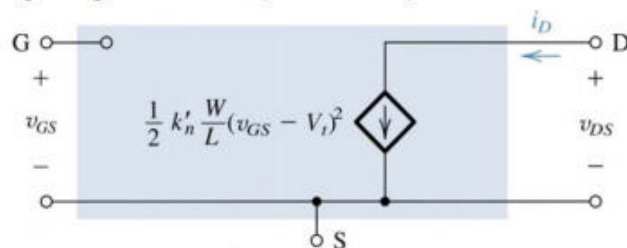
□ Triode region: ($v_{GS} > V_t$ and $v_{DS} < v_{GS} - V_t$)

$$\rightarrow i_D = \mu_n C_{ox} \frac{W}{L} [(v_{GS} - V_t)v_{DS} - \frac{1}{2}v_{DS}^2]$$

□ Saturation: ($v_{GS} > V_t$ and $v_{DS} \geq v_{GS} - V_t$)

$$\rightarrow i_D = \frac{1}{2} \mu_n C_{ox} \frac{W}{L} (v_{GS} - V_t)^2$$

□ large-signal model (saturation)



Derivation of the I-V relationship

- Induced charge in the channel due to MOS capacitor:

$$Q_I(x) = -C_{ox}[v_{GS} - V_t - v(x)]$$

- Equivalent resistance dR along the channel:

$$dR = \frac{dx}{qn(x)\mu_n h(x)W} = \frac{dx}{\mu_n W Q_I(x)}$$

- I-V derivations:

$$dv = i_D dR = \frac{i_D dx}{\mu_n W Q_I(x)} = \frac{i_D dx}{\mu_n C_{ox} W [v_{GS} - V_t - v(x)]}$$

$$\int_0^{v_{DS}} \mu_n C_{ox} W [v_{GS} - V_t - v(x)] dv = \int_0^L i_D dx$$

$$i_D = \mu_n C_{ox} \frac{W}{L} \left[(v_{GS} - V_t) v_{DS} - \frac{1}{2} v_{DS}^2 \right]$$

- Process transconductance parameter ($\mu A/V^2$): $k'_n = \mu_n C_{ox}$

- Aspect ratio: W/L

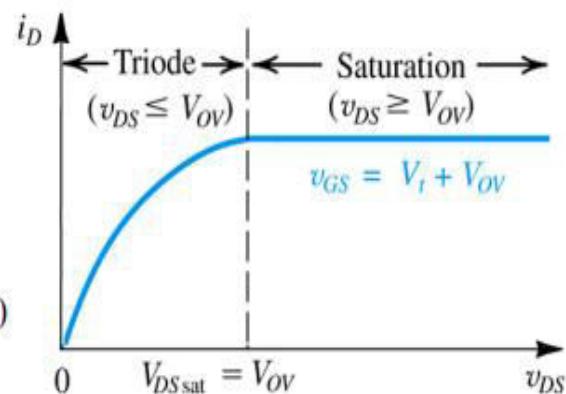
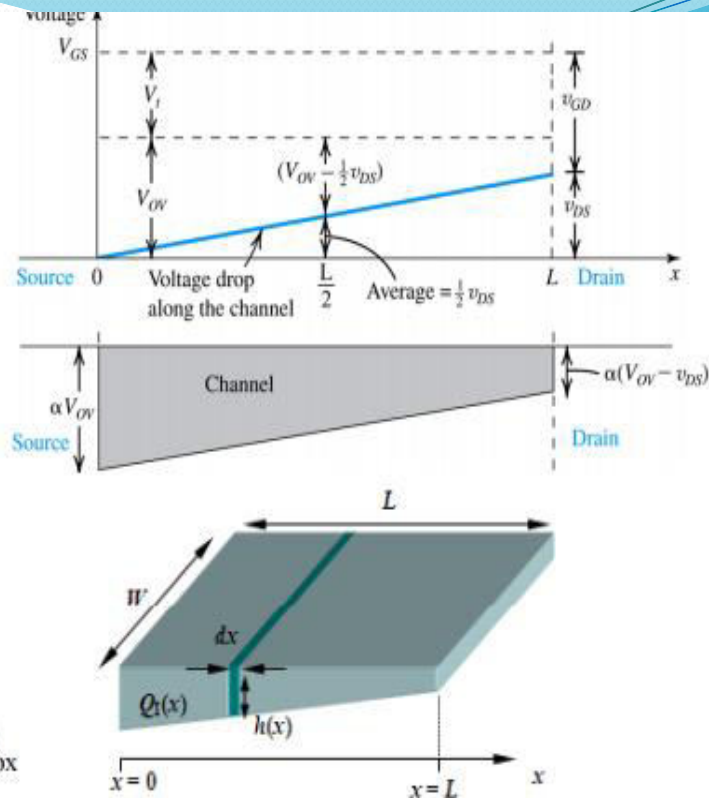
- Transconductance parameter ($\mu A/V^2$): $k_n = \mu_n C_{ox} (W/L)$

- Drain current of MOSFETs:

- Triode region: $i_D = k_n [(v_{GS} - V_t) v_{DS} - \frac{1}{2} v_{DS}^2]$

- Saturation region: $i_{Dsat} = \frac{1}{2} k_n (v_{GS} - V_t)^2$

- On-resistance (channel resistance for small v_{DS}): $r_{DS} = 1/k_n (v_{GS} - V_t)$

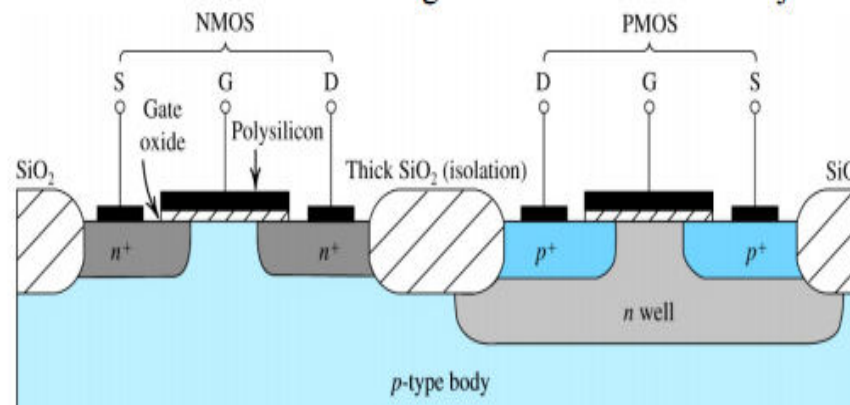


The p -channel enhancement-type MOSFET

- ❑ p -channel enhanced-type MOSFETs are fabricated on n -type substrate with p^+ source and p^+ drain.
- ❑ Normally, source is connected to high voltage and drain is connected to low voltage.
- ❑ As a negative voltage applies to gate electrode, negative charges accumulate in gate and the resulting field pushes electrons in n -type substrate away from the surface, leaving behind a carrier-depletion region.
- ❑ As gate voltage exceeds a negative **threshold voltage** V_t , holes start to accumulate on the substrate surface.
- ❑ The induced p region (**inversion layer**) thus forms a p -type channel for current flow from source to drain.
- ❑ Negative gate voltage is required to induce the channel → **enhancement-type** MOSFET.

Complementary MOS (CMOS)

- ❑ CMOS technology employs both PMOS and NMOS devices.
- ❑ If substrate is p -type, PMOS transistors are formed in n well (n -type body needed).
- ❑ If substrate is n -type, NMOS transistors are formed in p well (p -type body needed).
- ❑ The substrate and the well are connected to voltages which reverse bias the junctions for device isolation.



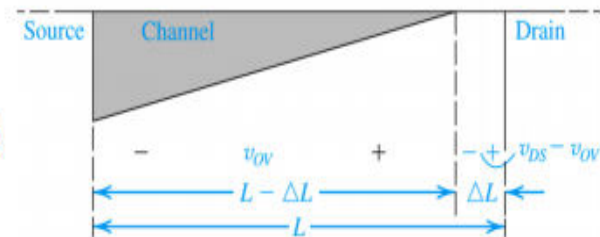
Channel length modulation

- ❑ Channel length modulation: the channel pinch-off point moves slightly away from drain as $v_{DS} > v_{DSsat}$.
- ❑ The effective channel length (L_{eff}) reduces with v_{DS} .
- ❑ Electrons travel to pinch-off point will be swept to drain by electric field.
- ❑ The length accounted for conductance in the channel is replaced by L_{eff} :

$$\int_0^{v_{GS}-V_t} k'_n W [v_{GS} - V_t - v(x)] dv = \int_0^{L_{eff}} i_D dx$$

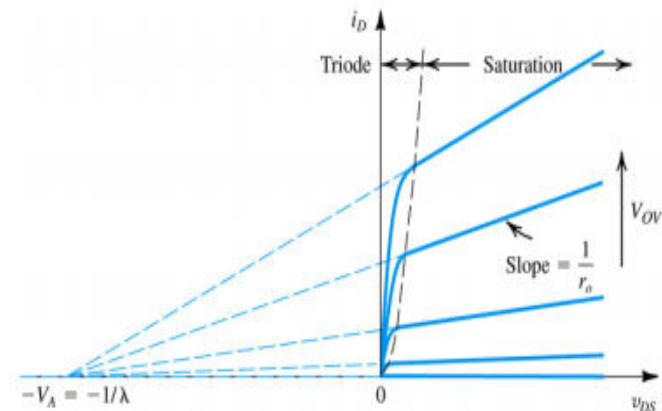
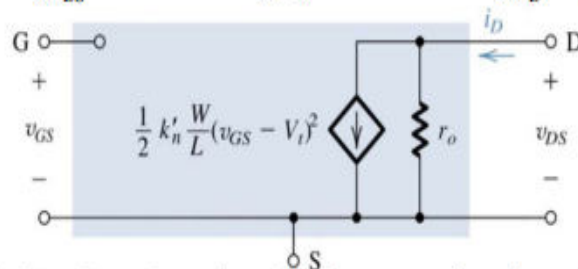
$$i_D = \frac{1}{2} k'_n \frac{W}{L_{eff}} (v_{GS} - V_t)^2 = \frac{1}{2} k'_n \frac{W}{L - \Delta L} (v_{GS} - V_t)^2 \approx \frac{1}{2} k'_n \frac{W}{L} (v_{GS} - V_t)^2 \left(1 + \frac{\Delta L}{L}\right)$$

assuming that $\frac{\Delta L}{L} \propto v_{DS} \rightarrow i_D = \frac{1}{2} k'_n \frac{W}{L} (v_{GS} - V_t)^2 (1 + \lambda v_{DS})$



Finite output resistance

$$r_o \equiv \left[\frac{\partial i_D}{\partial v_{DS}} \right]_{v_{GS}=\text{constant}} = \left[\lambda \frac{k'_n W}{2 L} (v_{GS} - V_t)^2 \right]^{-1} \approx \frac{1}{\lambda I_D} = \frac{V_A}{I_D}$$



- ❑ V_A (**Early voltage**) = $1/\lambda$ is proportional to channel length: $V_A = V'_A L$
- ❑ V'_A is process-technology dependent with a typical value from 5 ~ 50 V/μm.
- ❑ Due to the dependence of i_D on v_{DS} , MOSFET shows **finite output resistance** in saturation region.

The body effect

- ❑ The BS and BD junctions should be reverse biased for the device to function properly.
- ❑ Normally, the body of a n -channel MOSFET is connected to the most negative voltage.
- ❑ The depletion region widens in BS and BD junctions and under the channel as V_{SB} increases.
- ❑ **Body effect:** V_t increases due to the excess charge in the depletion region under the channel.
- ❑ The body effect can cause considerable degradation in circuit performance.
- ❑ Threshold voltage:

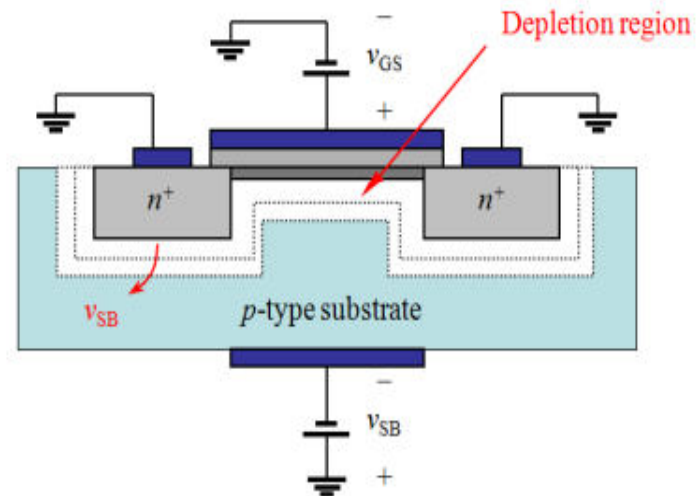
$$V_t = V_{t0} + \gamma [\sqrt{2\phi_f + V_{SB}} - \sqrt{2\phi_f}]$$

$$\text{where } \gamma = \frac{\sqrt{2qN_A\epsilon_{Si}}}{C_{ox}} \text{ and } \phi_f = \frac{kT}{q} \ln\left(\frac{N_A}{n_i}\right)$$

- ❑ Current equations:

$$i_D = \mu_n C_{ox} \frac{W}{L} [(v_{GS} - V_t)v_{DS} - \frac{1}{2}v_{DS}^2]$$

$$i_{Dsat} = \frac{1}{2} \mu_n C_{ox} \frac{W}{L} (v_{GS} - V_t)^2$$

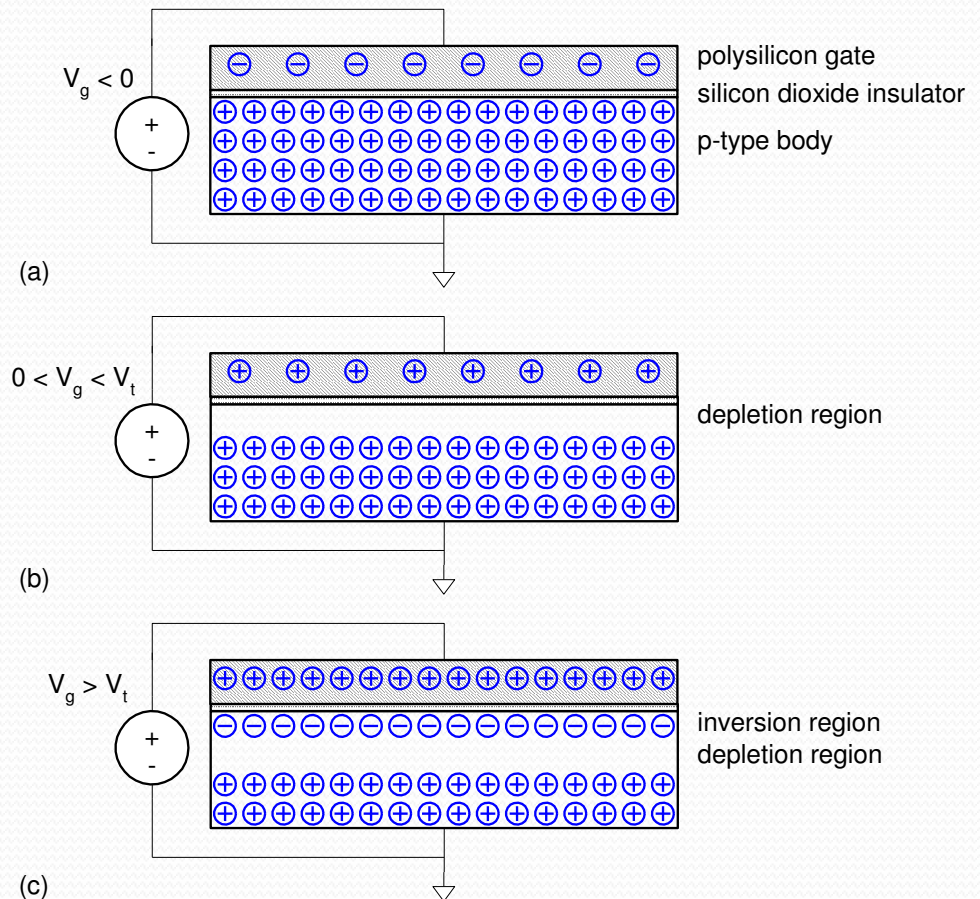


Temperature effect

- ❑ V_t decreases by $\sim 2\text{mV}$ for every 1°C rise $\rightarrow i_D$ increases with temperature.
- ❑ k'_n decreases with temperature $\rightarrow i_D$ decreases with increasing temperature.
- ❑ For a given bias voltage, the overall observed effect of a temperature increase is a decrease in i_D .

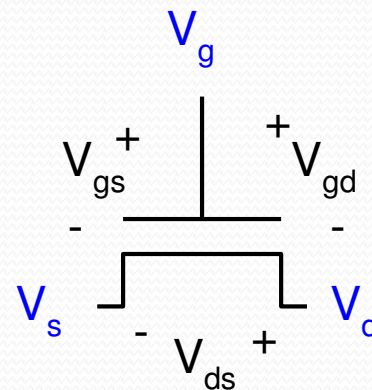
MOS Capacitor

- Gate and body form MOS capacitor
- Operating modes
 - Accumulation
 - Depletion
 - Inversion



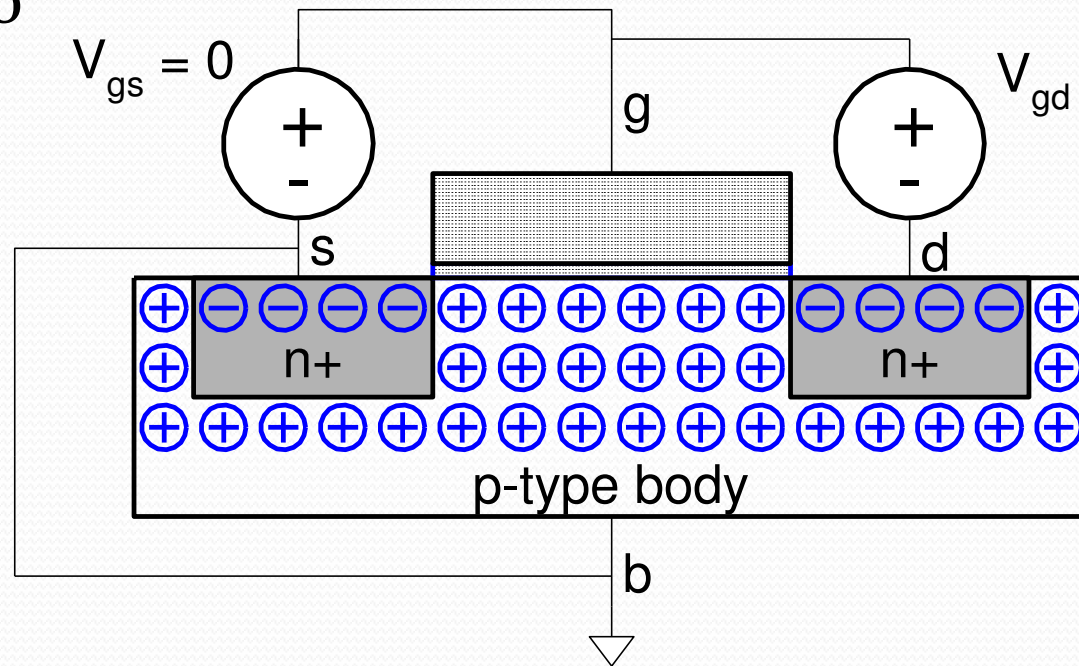
Terminal Voltages

- Mode of operation depends on V_g , V_d , V_s
 - $V_{gs} = V_g - V_s$
 - $V_{gd} = V_g - V_d$
 - $V_{ds} = V_d - V_s = V_{gs} - V_{gd}$
- Source and drain are **symmetric diffusion terminals**
 - By convention, source is terminal at lower voltage
 - Hence $V_{ds} \geq 0$
- NMOS body is grounded. First assume source is 0 too.
- Three regions of operation
 - Cutoff*
 - Linear*
 - Saturation*



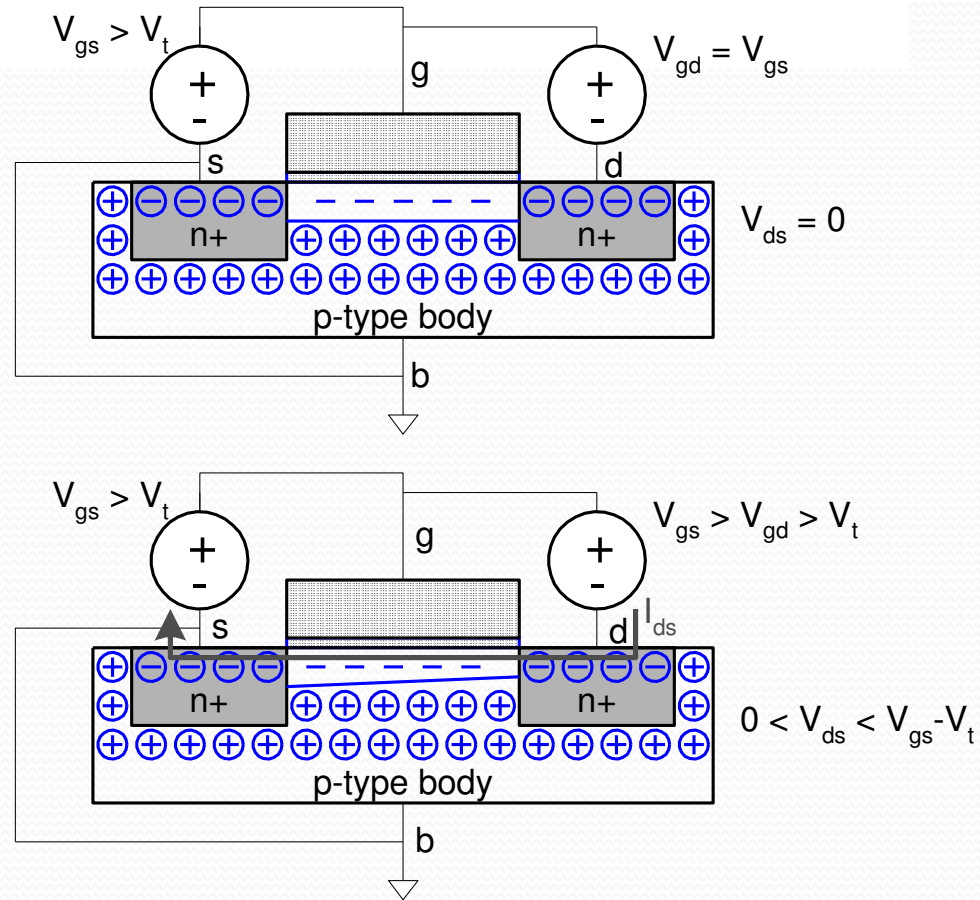
NMOS Cutoff

- No channel
- $I_{ds} = 0$



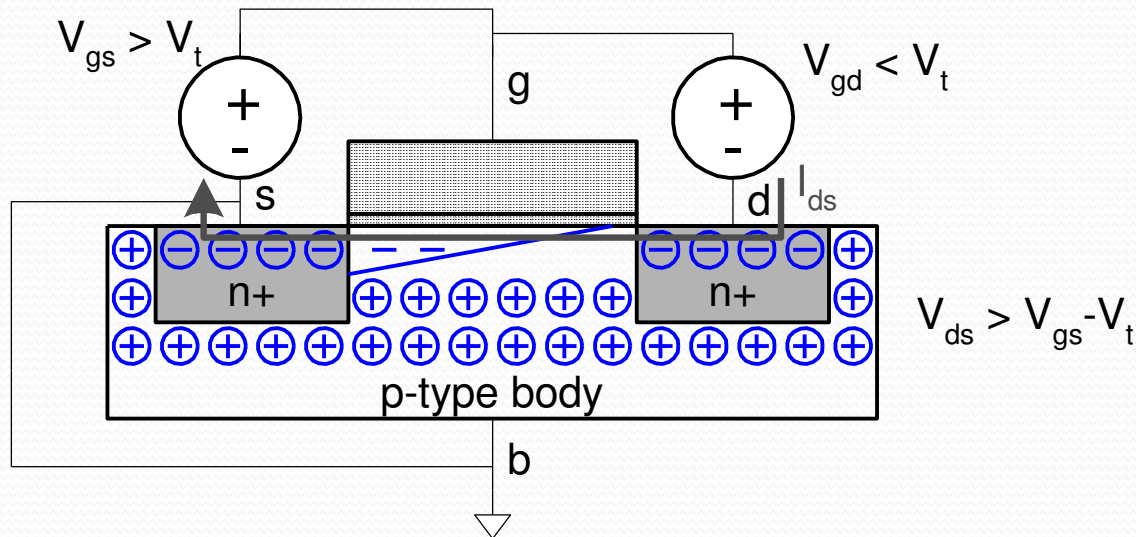
NMOS Linear

- Channel forms
- Current flows from d to s
 - e^- from s to d
- I_{ds} increases with V_{ds}
- Similar to **linear resistor**



NMOS Saturation

- Channel pinches off
- I_{ds} independent of V_{ds}
- We say current saturates
- Similar to current source



I-V Characteristics

- In Linear region, I_{ds} depends on
 - How much charge is in the channel?
 - How fast is the charge moving?

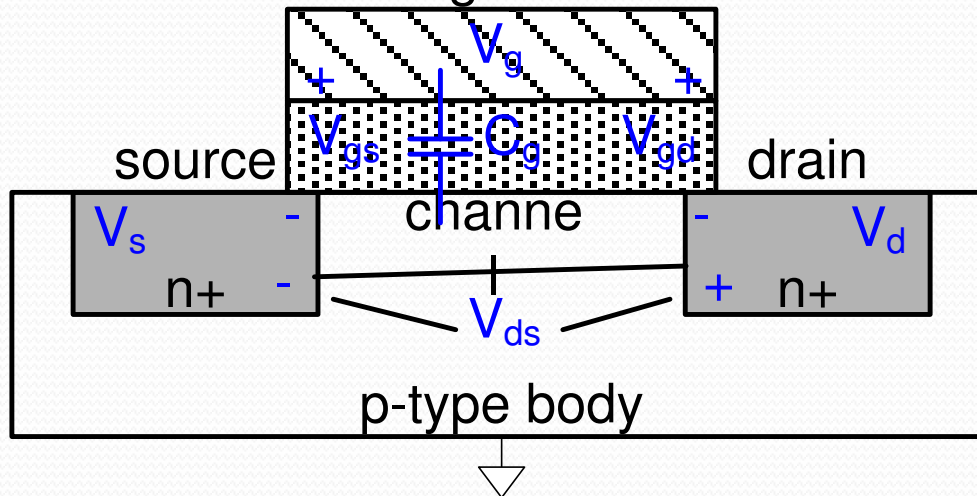
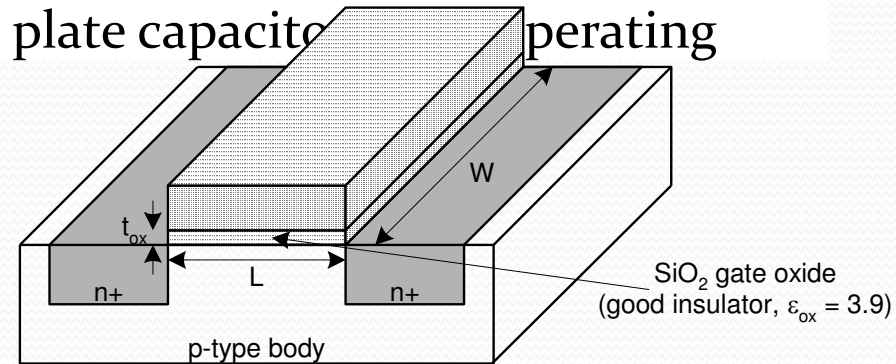
Channel Charge

- MOS structure looks like parallel plate capacitor operating in inversion
 - Gate - oxide - channel

- $Q_{\text{channel}} = CV$

- $C = C_g = \epsilon_{\text{ox}} WL / t_{\text{ox}} = C_{\text{ox}} WL$

- $V = V_{\text{gc}} - V_t = (V_{\text{gs}} - V_{\text{ds}}/2) - V_t$



$$C_{\text{ox}} = \epsilon_{\text{ox}} / t_{\text{ox}}$$

$$V_{\text{gc}} = (V_{\text{gs}} + V_{\text{gd}}) / 2$$

$$= V_{\text{gs}} - V_{\text{ds}} / 2$$

Carrier velocity

- Charge is carried by e-
- Carrier velocity v **proportional** to lateral E-field between source and drain
- $v = \mu E$ (μ is called mobility)
- $E = V_{ds}/L$
- Time for carrier to cross channel:
 - $t = L / v$

NMOS Linear I-V

- Now we know
 - How much **charge** Q_{channel} is in the channel
 - How much **time** t each carrier takes to cross

$$I_{ds} = \frac{Q_{\text{channel}}}{t}$$

$$= \mu C_{\text{ox}} \frac{W}{L} \left(V_{gs} - V_t - \frac{V_{ds}}{2} \right) V_{ds} \quad \beta = \mu C_{\text{ox}} \frac{W}{L}$$

$$= \beta \left(V_{gs} - V_t - \frac{V_{ds}}{2} \right) V_{ds}$$

NMOS Saturation I-V

- If $V_{gd} < V_t$, channel **pinches off** near drain
 - When $V_{ds} > V_{dsat} = V_{gs} - V_t$
- Now drain voltage **no longer** increases current

$$I_{ds} = \beta \left(V_{gs} - V_t - \frac{V_{dsat}}{2} \right) V_{dsat}$$
$$= \frac{\beta}{2} (V_{gs} - V_t)^2$$

NMOS I-V Summary

- Shockley 1st order transistor models (**long-channel**)

$$I_{ds} = \begin{cases} 0 & V_{gs} < V_t & \text{cutoff} \\ \beta \left(V_{gs} - V_t - \frac{V_{ds}}{2} \right) V_{ds} & V_{ds} < V_{dsat} & \text{linear} \\ \frac{\beta}{2} (V_{gs} - V_t)^2 & V_{ds} > V_{dsat} & \text{saturation} \end{cases}$$

Example

- We consider a 0.6 μm process

- From AMI Semiconductor

- $t_{\text{ox}} = 100 \text{ \AA}$

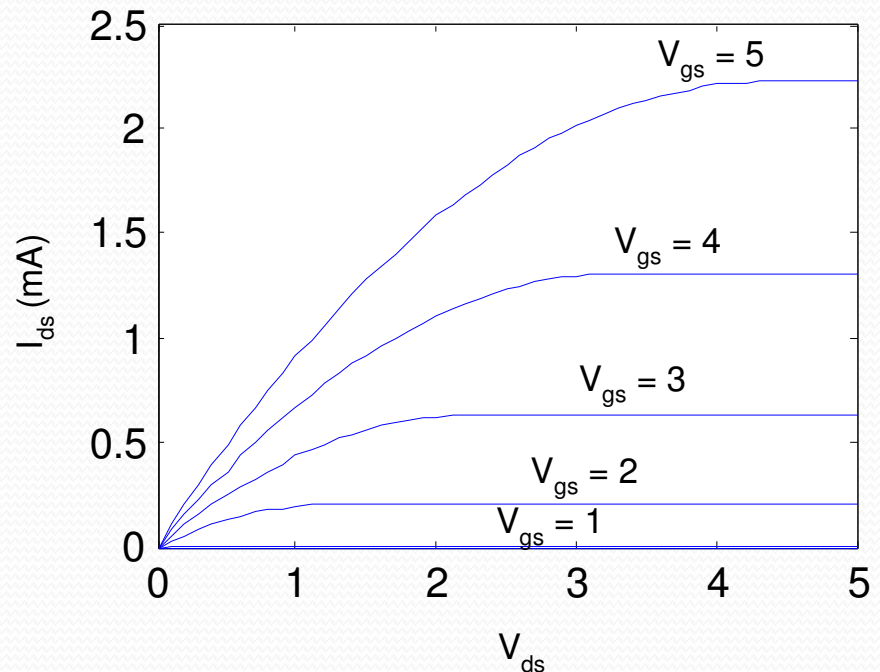
- $\mu = 350 \text{ cm}^2/\text{V}^*\text{s}$

- $V_t = 0.7 \text{ V}$

- Plot I_{ds} vs. V_{ds}

- $V_{\text{gs}} = 0, 1, 2, 3, 4, 5$

- Use $W/L = 4/2 \lambda$



$$\beta = \mu C_{\text{ox}} \frac{W}{L} = (350) \left(\frac{3.9 \bullet 8.85 \cdot 10^{-14}}{100 \cdot 10^{-8}} \right) \left(\frac{W}{L} \right) = 120 \frac{W}{L} \mu\text{A}/\text{V}^2$$

PMOS I-V

- All dopings and voltages are inverted for PMOS
- Mobility μ_p is determined by holes
 - Typically **2-3x lower** than that of electrons μ_n
 - $120 \text{ cm}^2/\text{V}^*\text{s}$ in AMI $0.6 \mu\text{m}$ process
- Thus PMOS must be **wider** to provide same current
 - In this class, **assume** $\mu_n / \mu_p = 2$